IFIL



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Masahiro FURUSAWA et al.

Application No.: 10/028,712

Group Art Unit: 1762

Examiner:

W. Markham

Filed: December 28, 2001

Docket No.:

111604

For:

A METHOD FOR FABRICATING A SILICON THIN-FILM

AMENDMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In reply to the November 18, 2003 Office Action, please consider the following:

Amendments to the Specification;

Amendments to the Claims as reflected in the listing of claims; and

Remarks.